

## **2018**

Zolotov PI, Divochiy AV, Vakhtomin YB, Lubchenko AV, Morozov PV, Shurkaeva IV, et al. Influence of sputtering parameters on the main characteristics of ultra-thin vanadium nitride films. In: J. Phys.: Conf. Ser. Vol 1124.; 2018. 051030.